

# LECTURE SCHEDULE

Mon (Ke3) 12.15 – 14.00  
Wed (Ke2) 10.15 – 12.00  
Fri (Ke5) 10.15 – 12.00

	Date	Topic
1.	Wed 06.09.	Course Introduction & Short Review on Elements & Periodic Table
2.	Fri 08.09.	Short Survey of Main Group Elements
3.	Mon 11.09.	Zn + Ti, Zr, Hf & Atomic Layer Deposition (ALD)
4.	Wed 13.09.	Transition Metals: General Aspects & Pigments
5.	Fri 15.09.	Redox Chemistry (Ke4)
6.	Mon 18.09.	Crystal Field Theory
7.	Wed 20.09.	V, Nb, Ta & Perovskites & Metal Complexes & MOFs & MLD
8.	Mon 25.09.	Cr, Mo, W & 2D materials & Mxenes & Layer-Engineering
9.	Wed 27.09.	Mn, Fe, Co, Ni, Cu
10.	Fri 29.09.	Cu & Magnetism & Superconductivity
11.	Mon 02.10.	Ag, Au, Pt, Pd & Catalysis (Antti Karttunen)
12.	Wed 04.10.	Lanthanoids + Actinoids & Luminescence
	Fri 06.10.	
13.	Wed 11.10.	Resources of Elements & Rare/Critical Elements & Element Substitutions
14.	Fri 13.10.	Inorganic Materials Chemistry Research

**EXAM: Tuesday Oct. 17, 9:00-12:00 in Ke2**

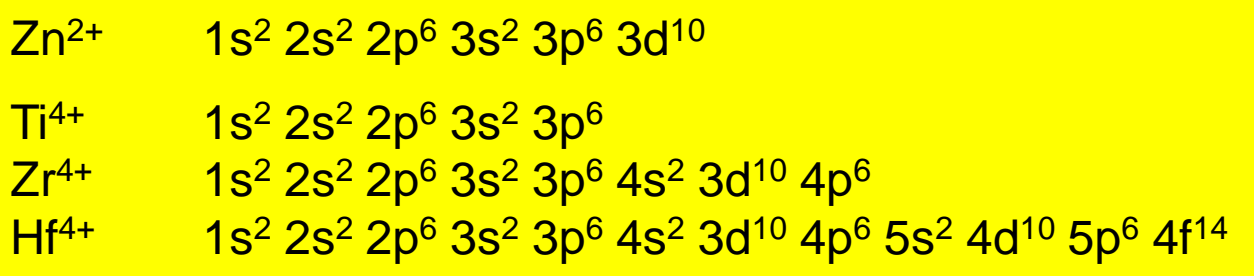
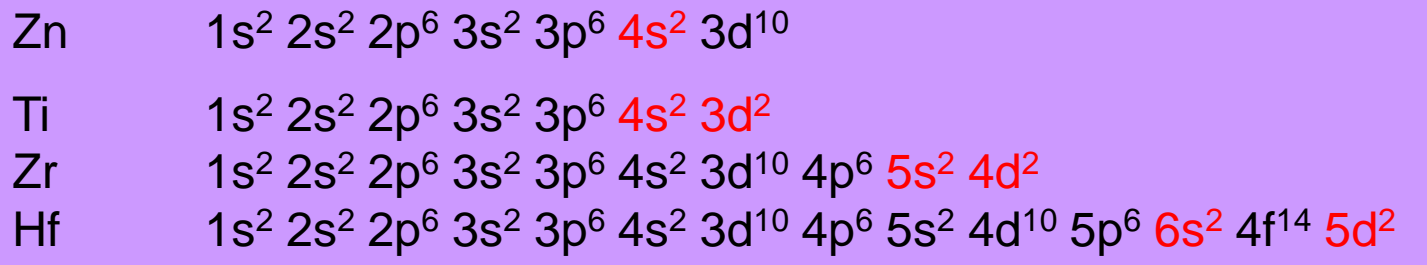
# PRESENTATION TOPICS/SCHEDULE

Mon	25.09.	Mo:	
Wed	27.09.	Mn:	Naomi Lyle & Sanni Ilmaranta
		Ru:	Miklos Nemeszeghy & Timo de Jonge
Fri	29.09.	Cu:	Koshila Hiruni & Kaushalya Poonanoo
Wed	04.10.	Eu:	Binglu Wang & Maryam Jafarishiad & <b>Saara Siekkinen</b>
		Nd:	Patrich Wiesenfeldt & Tomoki Nakayama
		U:	Miikka Viirto & Ashish Singh
Wed	11.10.	Co:	Gabrielle Laurent & Yan Zheng
		In:	Sonja Alasaukko-oja & Katri Haapalinna
		Te:	Sofia Rantala & Roger Peltonen

## QUESTIONS: Lecture 3

1. Among the following four elements, Zn, Ti, Zr, and Hf, only one forms compounds at +III oxidation state. Just by looking at the Periodic Table, predict which element this is. Most importantly, explain why you predicted so.
2. Hf is mostly found in nature in trace amounts in Zr minerals. Why it is so easy for Hf to replace some of the Zr in these minerals?
3. Which element is commonly used as a substituent to create oxygen vacancies in  $\text{ZrO}_2$ ? Explain why ?
4. Why in ALD technique:
  - (a) Film thickness control is straightforward?
  - (b) Conformal coating is readily achieved?

Group→	1	2	3	4	5	6	7	8	9	10	11	12	13	14	15	16	17	18	
↓Period																			
1	1 H																		2 He
2	3 Li	4 Be											5 B	6 C	7 N	8 O	9 F	10 Ne	
3	11 Na	12 Mg											13 Al	14 Si	15 P	16 S	17 Cl	18 Ar	
4	19 K	20 Ca	21 Sc	22 Ti	23 V	24 Cr	25 Mn	26 Fe	27 Co	28 Ni	29 Cu	30 Zn	31 Ga	32 Ge	33 As	34 Se	35 Br	36 Kr	
5	37 Rb	38 Sr	39 Y	40 Zr	41 Nb	42 Mo	43 Tc	44 Ru	45 Rh	46 Pd	47 Ag	48 Cd	49 In	50 Sn	51 Sb	52 Te	53 I	54 Xe	
6	55 Cs	56 Ba	*	72 Hf	73 Ta	74 W	75 Re	76 Os	77 Ir	78 Pt	79 Au	80 Hg	81 Tl	82 Pb	83 Bi	84 Po	85 At	86 Rn	
7	87 Fr	88 Ra	**	104 Rf	105 Db	106 Sg	107 Bh	108 Hs	109 Mt	110 Ds	111 Rg	112 Cn	113 Uut	114 Fl	115 Uup	116 Lv	117 Uus	118 Uuo	



**No partly-filled  
d or f orbitals**

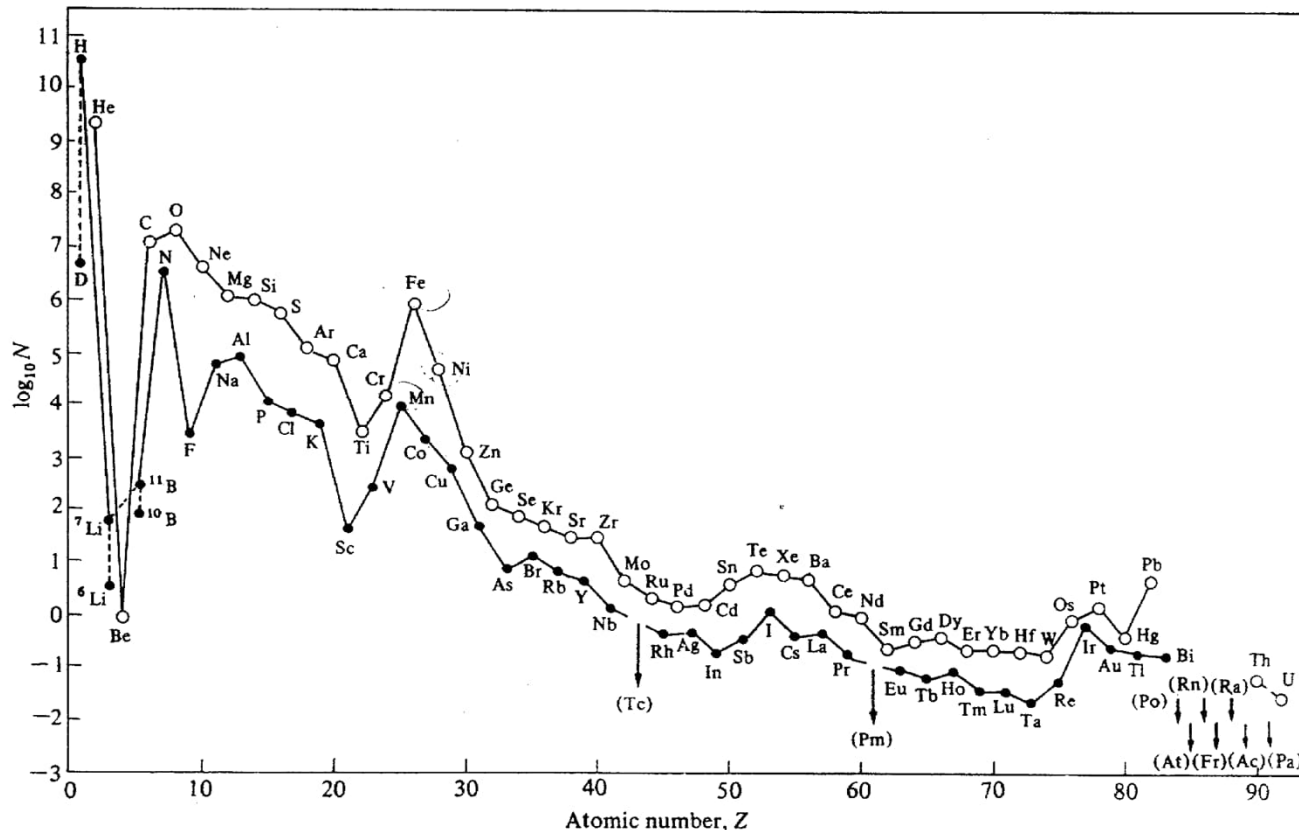
# IONIC RADII (in Å): Depending on Coordination Number

		Ti	Zr	Hf	Zn
<b>+2</b>	<b>CN-4</b>	-	-	-	<b>0.60</b>
	<b>CN-5</b>	-	-	-	<b>0.68</b>
	<b>CN-6</b>	<b>0.86</b>	-	-	<b>0.74</b>
	<b>CN-8</b>	-	-	-	<b>0.90</b>
<b>+3</b>	<b>CN-4</b>	-	-	-	-
	<b>CN-5</b>	-	-	-	-
	<b>CN-6</b>	<b>0.67</b>	-	-	-
<b>+4</b>	<b>CN-4</b>	<b>0.42</b>	<b>0.73</b>	<b>0.72</b>	-
	<b>CN-5</b>	<b>0.51</b>	-	-	-
	<b>CN-6</b>	<b>0.61</b>	<b>0.86</b>	<b>0.85</b>	-
	<b>CN-8</b>	<b>0.74</b>	<b>0.98</b>	<b>0.97</b>	-

<http://abulafia.mt.ic.ac.uk/shannon/ptable.php>

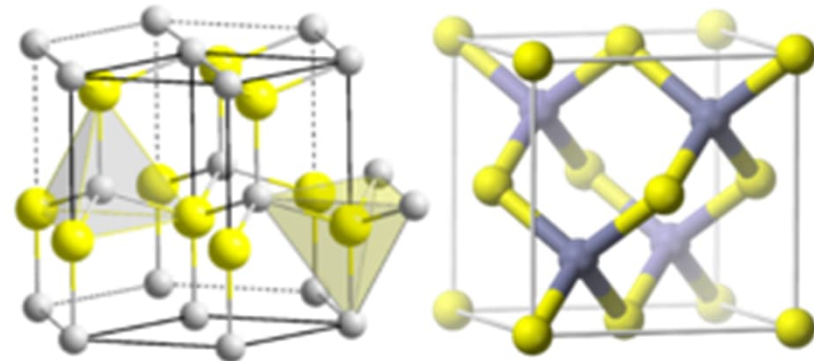
# OCCURRENCE of the METALS: Zn, Ti, Zr, Hf

- **Zn** ( $d^{10}$ , not transition metal) is the fourth most common metal in use (after Fe, Al and Cu) with an annual production of ca. 13 million tonns
- **Ti**: widely distributed, many minerals (most common rutile and ilmenite)
- **Zr**: found in more than 40 minerals
- **Hf**: quite rare, no own minerals, traces in Zr minerals:  $Hf/Zr \approx 2 \%$



# ZnO

- 4-coordination in hexagonal wurtzite & cubic zinc blende (diamond like) structures
- Additive in various applications: rubbers, plastics, ceramics, glass, cement, lubricants, paints, ointments, adhesives, sealants, pigments, foods, batteries, ferrites, fire retardants, first-aid tapes, etc.
- **Wide-bandgap** II-VI semiconductor
- Native doping due to small excess of zinc/hydrogen → n-type doping
- Al<sup>3+</sup>-for-Zn<sup>2+</sup> doping for enhanced n-type doping
- Problem for some applications): p-type doping has not been achieved
- Attractive properties for optoelectronics: wide bandgap, high transparency, tunable electrical properties, high electron mobility → transparent electrodes, liquid crystal displays, energy-saving windows, electronics as thin-film transistors and light-emitting diodes → THIN FILMS



# Zinc in Biology (protein functions)

- Essential for humans, animals and plants
- Crucial for the catalytic functions in enzymes
- Stabilizes the folding of protein subdomains
- Why Zinc ?
  - **widely available** in environment (important for evolution)
  - **fixed oxidation state** (+II): completely resistant to redox changes and thus not affected by redox potentials in the organisms
  - prefers **tetrahedral coordination** (unlike many other metals): tetrahedral coordination of the metal site seems to be a key feature in most zinc enzymes
  - $d^{10}$  configuration and **no crystal field effect** (to be discussed next week): flexible for adjustment of nearest-neighbour surroundings



## **TITANIUM: Use as a metal / in metal alloys**

- **Corrosion resistance**: pulp and marine industry, chemical processing, and energy production/storage applications
- **High specific strength** (strength/weight ratio): automotive industry, aerospace applications, sports equipment, jewelry, eyeglass frames
- **Inertness in human body**: surgery/artificial implants
- **DISADVANTAGE**: cost (Ti 6 times more expensive than Al)

# PRODUCTION OF TITANIUM

- **Oxide minerals:** rutile ( $\text{TiO}_2$ ) or ilmenite ( $\text{FeO-TiO}_2$ ; 97-98 %  $\text{TiO}_2$ )
- Oxides are transformed to  $\text{TiCl}_4$  which is a **liquid** and can be distilled for purification, e.g. by chloride process:
  - $\text{TiO}_2 + 2\text{Cl}_2 + 2\text{C} (800^\circ\text{C}) \rightarrow \text{TiCl}_4 + 2\text{CO}$
  - $2\text{TiFeO}_3 + 7\text{Cl}_2 + 6\text{C} (900^\circ\text{C}) \rightarrow 2\text{TiCl}_4 + 2\text{FeCl}_3 + 6\text{CO}$
- $\text{TiCl}_4$  is reduced in argon with molten Mg (**Kroll process**)
  - $\text{TiCl}_4 + 2\text{Mg} (1100^\circ\text{C}) \rightarrow \text{Ti} + 2\text{MgCl}_2$
- $\text{MgCl}_2$  is reduced back to Mg such that it can be **recycled**
- Product: **Titanium sponge** (porous)

# Zr & Hf

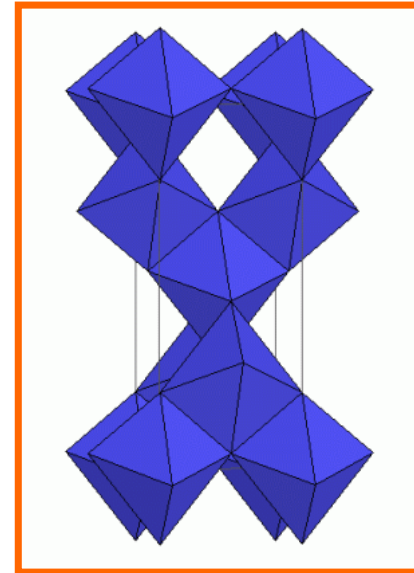
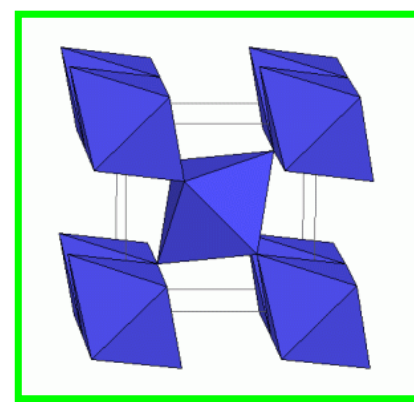
- Exactly the same size (due to shielding effect/lanthanide contraction)
- Of all the 4d-5d transition metal pairs, Zr and Hf are the most similar
- Separation of Hf from Zr very difficult
- Hf was discovered as late as 1922 (Zr more than 100 years earlier)
- Hf was the first element which was searched for and found based on the quantum theory (lat. *Hafnia* = Copenhagen)
- Differences:
  - density (atomic weight ratio Zr:Hf = 1.0:2.0)
  - neutron absorption (Hf 600-times stronger):  
different (opposite) uses in nuclear power plants

## SEPARATION of Zr and Hf

- **Zr**: very low neutron absorption → used to make containers for nuclear fuel
- **Hf**: very high neutron absorption → used in control rods
- For the use of Zr in nuclear fuel containers it is crucial to ensure that the Zr metal used has extremely low Hf content

# TiO<sub>2</sub> (important chemical, produced worldwide)

- **Crystal structures:** - **rutile**, **anatase**, brookite (6-coord.)
- **White pigment:** - large refractive index  
- used in paints, paper, plastics, cosmetics, foods, tooth pastes, ...
- **UV protection:** - sunscreens, plastics
- **Inert/non-poisonous:** - filler material in pharmaceuticals
- **Photocatalytic:** - Akira Fujishima 1970s  
- water splitting
- **Antibacterial:** - decomposition of organics with UV light  
- 3-times stronger compared to chlorine,  
1.5-times stronger compared to ozone
- **Superhydrophilic:** - Akira Fujishima 1996  
- after UV radiation  
- water spreads (no droplets) on TiO<sub>2</sub>  
- e.g. sauna mirrors

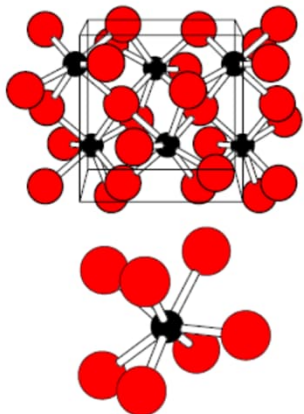


# ZrO<sub>2</sub>

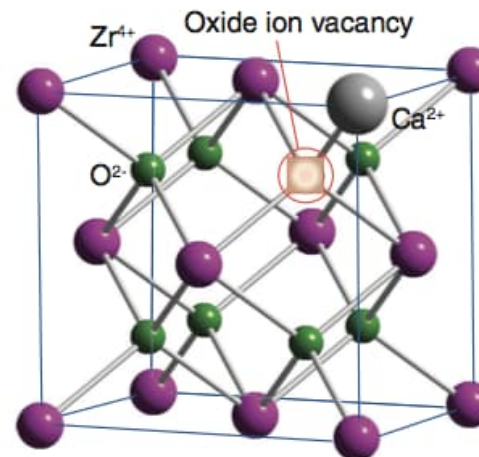
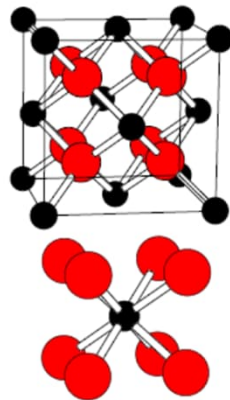
- Used as industrial ceramics, protective coating (e.g. on TiO<sub>2</sub> pigment particles) and refractory material in e.g. insulation
- Monoclinic (7-coord.) structure at RT & cubic (8-coord.) structure at high temperatures
- Y<sup>III</sup>-for-Zr<sup>IV</sup> substitution stabilizes the cubic ZrO<sub>2</sub> structure
- Yttrium-stabilized zirconia (YSZ) for oxygen sensors and fuel cells owing to its low electronic conductivity but high oxide ion conductivity (Y<sup>3+</sup> → Zr<sup>4+</sup> → oxygen vacancies)
- Synthesized in various colours (gemstone & diamond simulant)



Room Temperature  
Monoclinic (P2<sub>1</sub>/c)  
7 coordinate Zr  
4 coord. + 3 coord. O<sup>2-</sup>

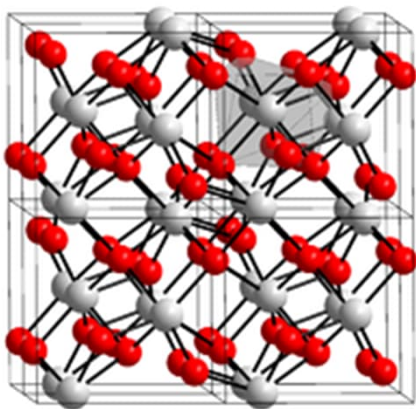


High Temperature  
Cubic (Fm3m)  
cubic coordination for Zr  
tetrahedral coord. for O<sup>2-</sup>



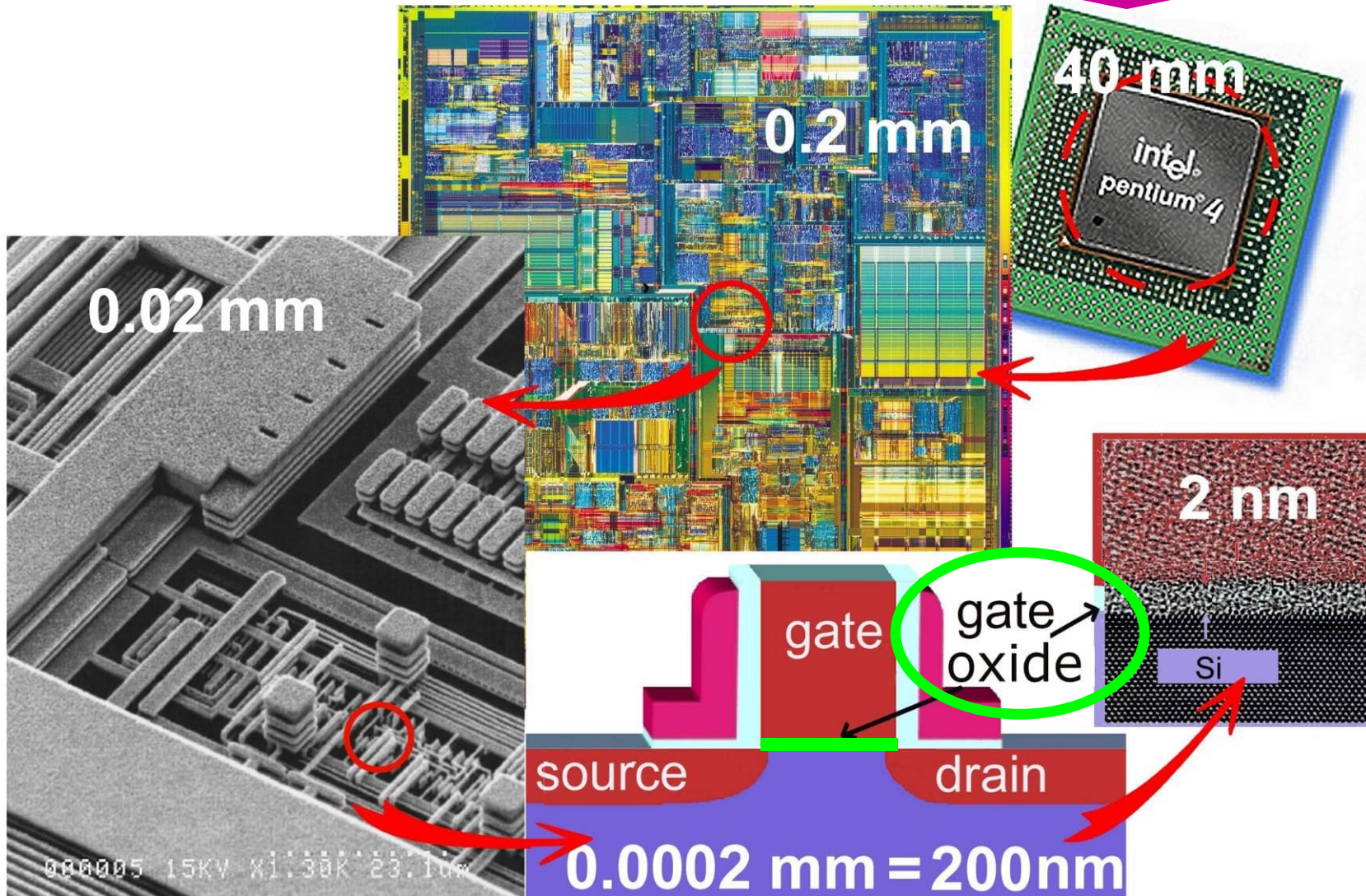
# HfO<sub>2</sub>

- Similar monoclinic (7-coord.) crystal structure to that of ZrO<sub>2</sub>
- Very high melting point → refractory material for insulation (e.g. in thermocouples)  
→ operates up to 2500 °C
- Multilayered HfO<sub>2</sub> coatings reflect sunlight & block heat conduction  
→ passive cooling of buildings  
→ several degrees cooler than surrounding materials
- **HfO<sub>2</sub> high-κ dielectrics** → dielectric constant 5 times higher compared to SiO<sub>2</sub>  
→ high-κ material in DRAM (dynamic random access memory) and CMOS (complementary metal-oxide semiconductor) microelectronics devices
- Intel 2007 → replacement of SiO<sub>2</sub> as gate insulator in FETs (field-effect transistor)  
→ deposition of high-quality amorphous THIN FILMS using ALD
- Partial substitution of Hf by Si (or Al) increases the crystallization temperature



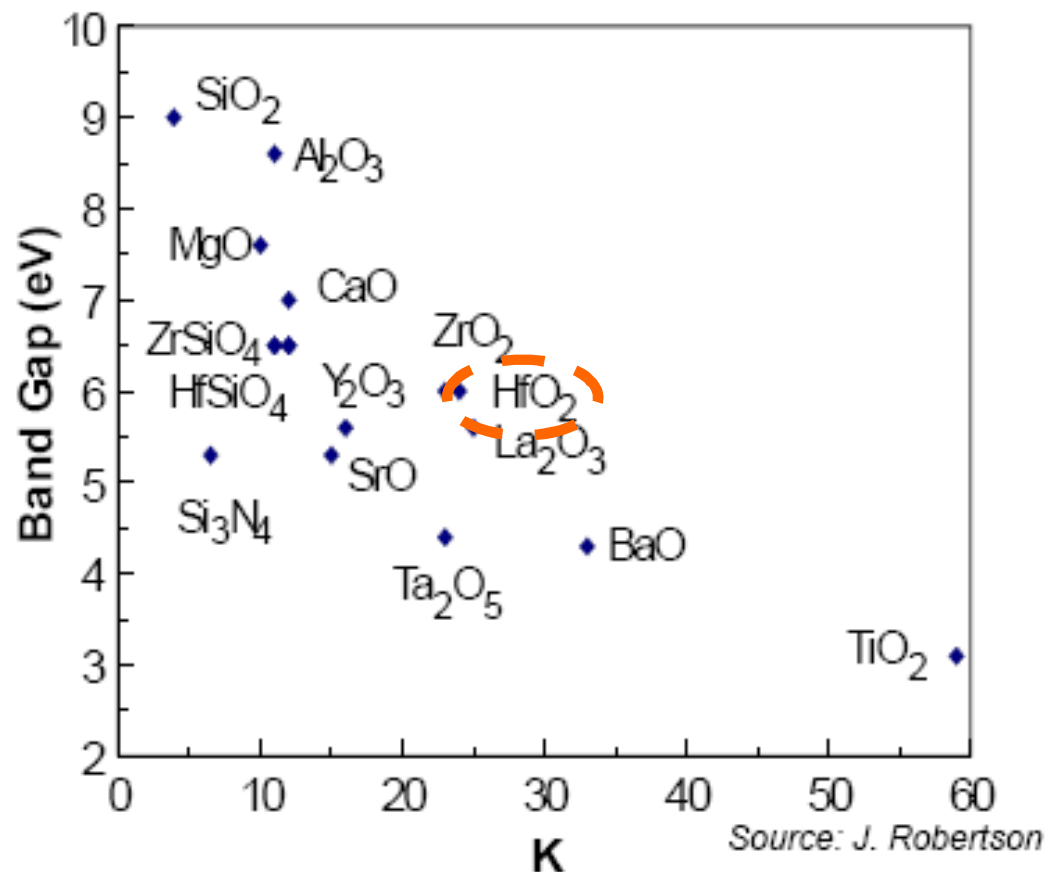
# CMOS transistor

smaller transistors → lower gate voltage  
same electric fields → thinner dielectric  
 $\text{SiO}_2 \rightarrow$  **HIGH- $k$  DIELECTRICS**



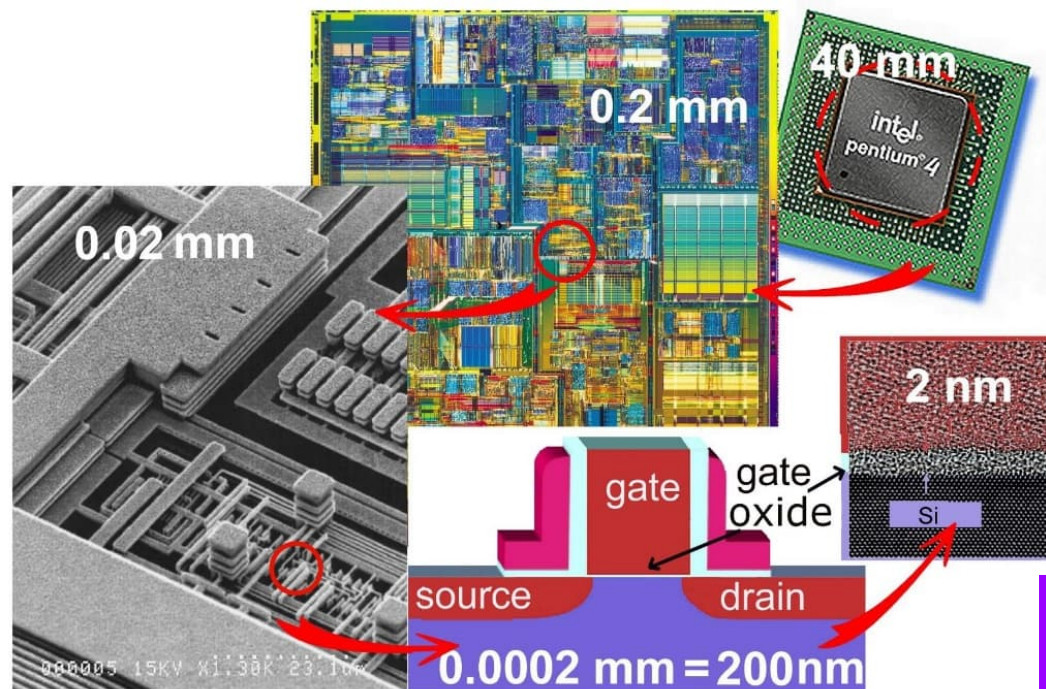
## Conditions for high- $k$ dielectrics

- High enough **dielectric constant  $k$**
- Wide **band gap** for low leakage
- **Stable** – no reaction with Si
- **Good interface, low impurities**





# Atomic Layer Deposition (ALD) Technology

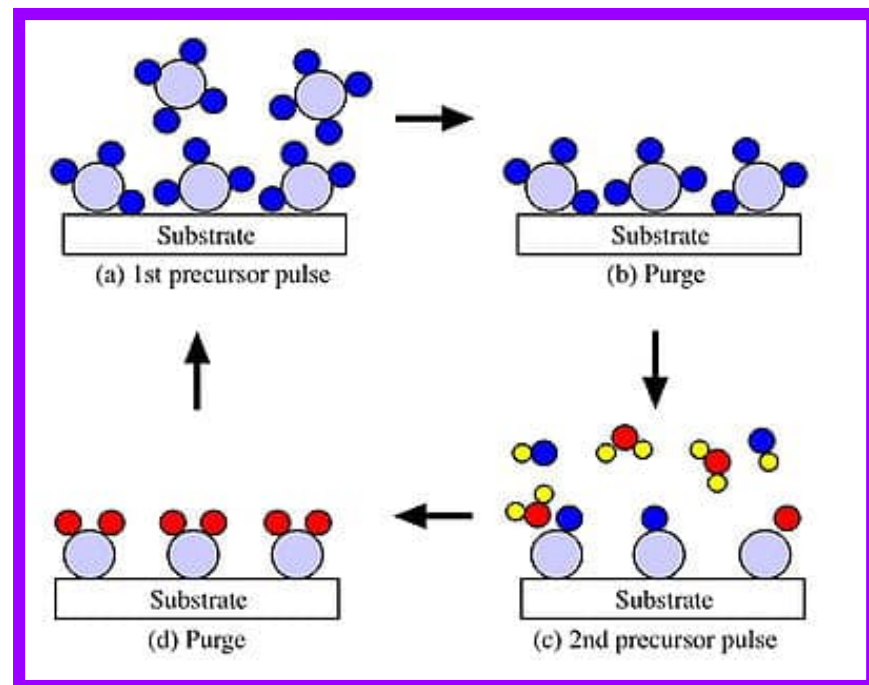


- High-quality (pinhole-free)
- Thickness control (atomic level)
- Large-area homogeneity
- Conformity → Nanostructuring

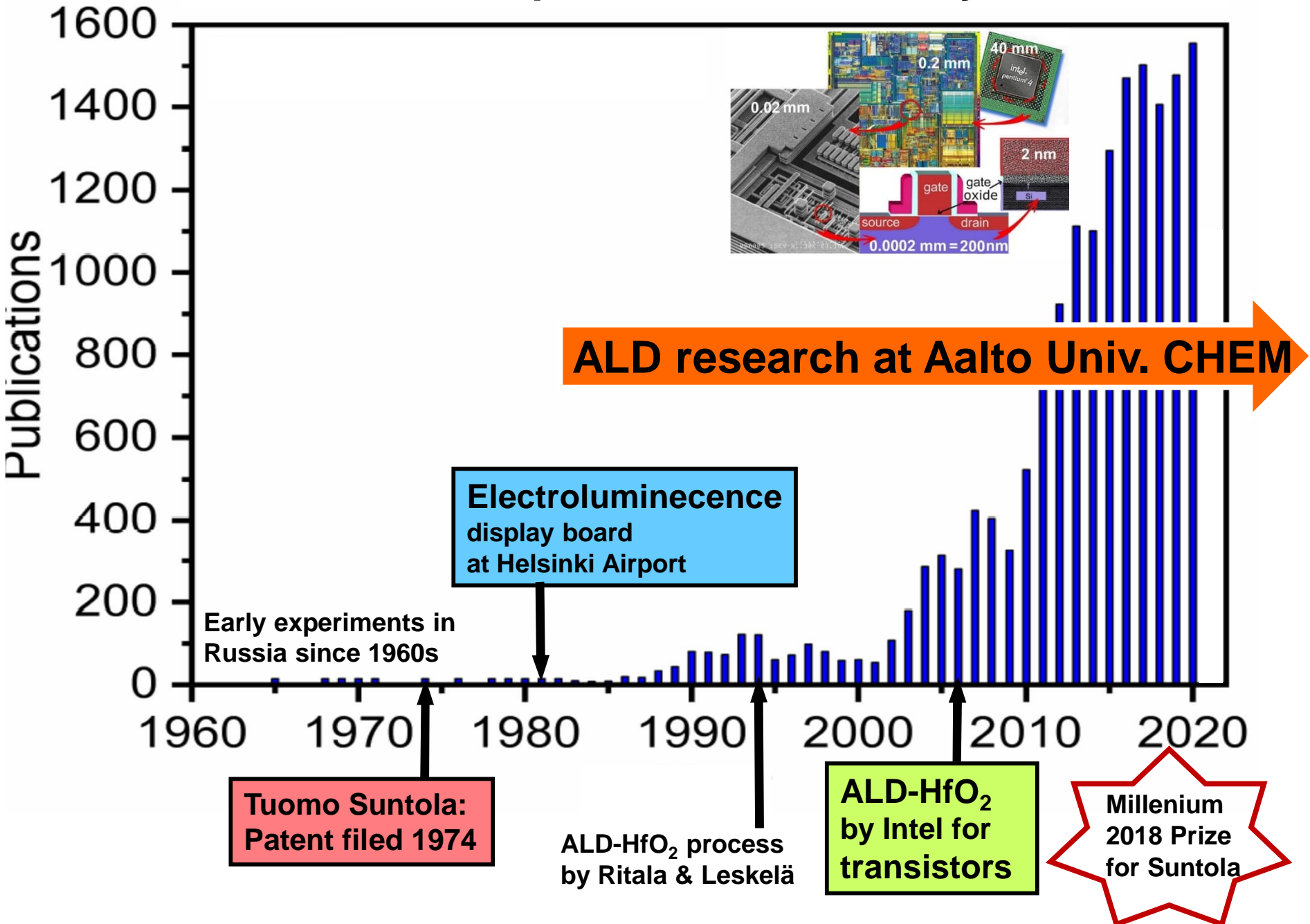
ALD:  $\text{HfCl}_4 + \text{H}_2\text{O}$

## CMOS transistor

- 2-nm amorphous  $\text{HfO}_2$  gate-oxide layer deposited by ALD

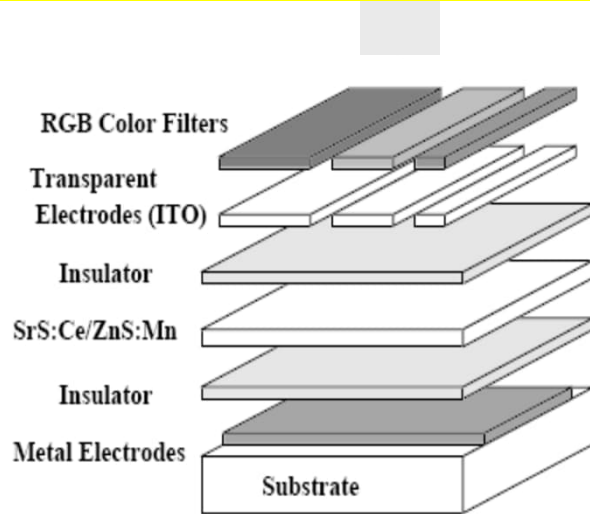


# ALD publications annually



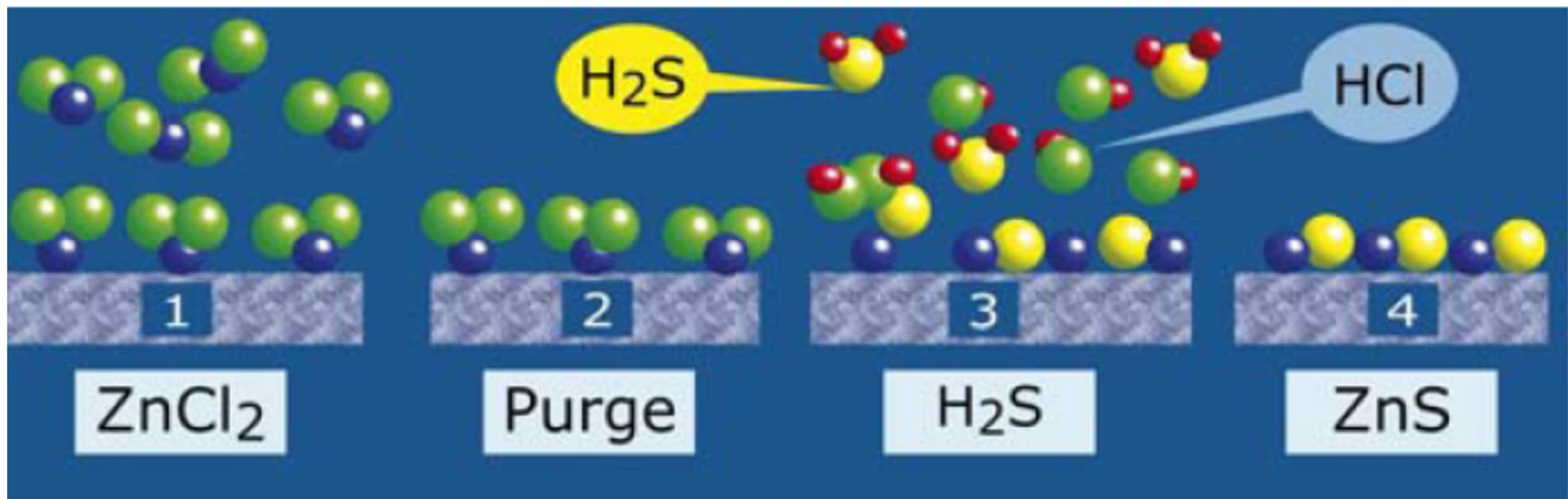
# Atomic Layer Deposition (ALD) Thin-Film Technique

- Gaseous precursors & Self-limiting surface reactions
- Precisely thickness-controlled, Large-area homogeneous & Conformal thin films



Electroluminescent display

Instrumentarium/Finlux/Planar



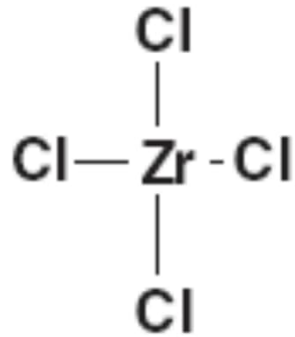


# **OXIDES ( $\text{Al}_2\text{O}_3$ , $\text{ZnO}$ , $\text{TiO}_2$ , $\text{ZrO}_2$ & $\text{HfO}_2$ ) & ALD (atomic layer deposition) thin-film technology**

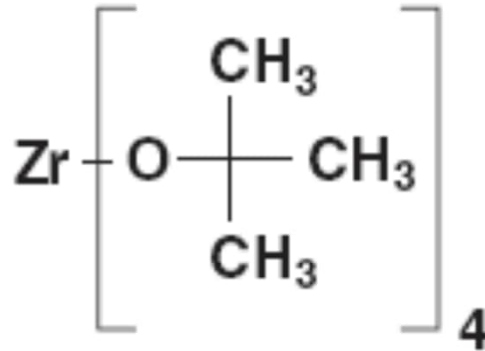
## **EXAMPLES of APPLICATIONS**

- ALD- $\text{HfO}_2$  (amorphous): high-k dielectrics
- ALD- $\text{ZrO}_2$  (amorphous): barrier coating
- ALD- $\text{TiO}_2$  (crystalline): photovoltaics
- ALD- $\text{ZnO}$  (crystalline): thermoelectric material

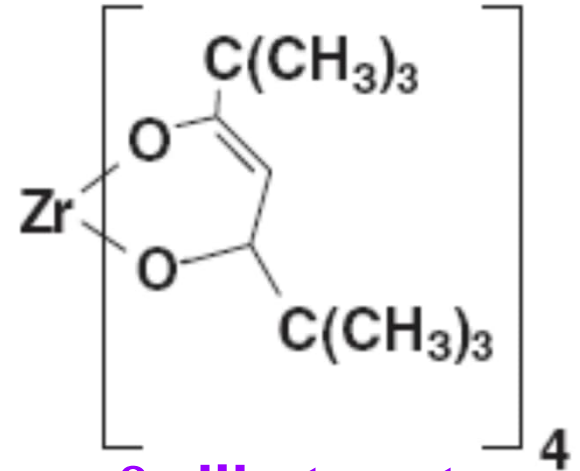
# COMMON PRECURSORS in ALD



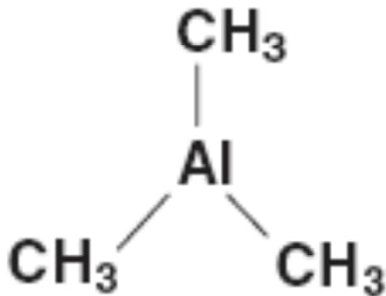
halides



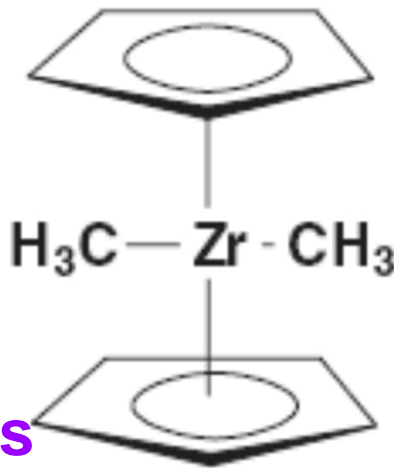
alkoxides



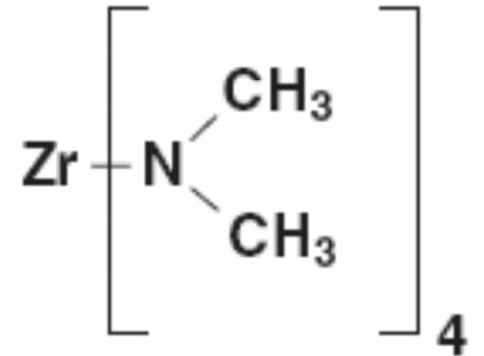
$\beta$ -diketonates



organometallics



e.g. cyclopentadienyls

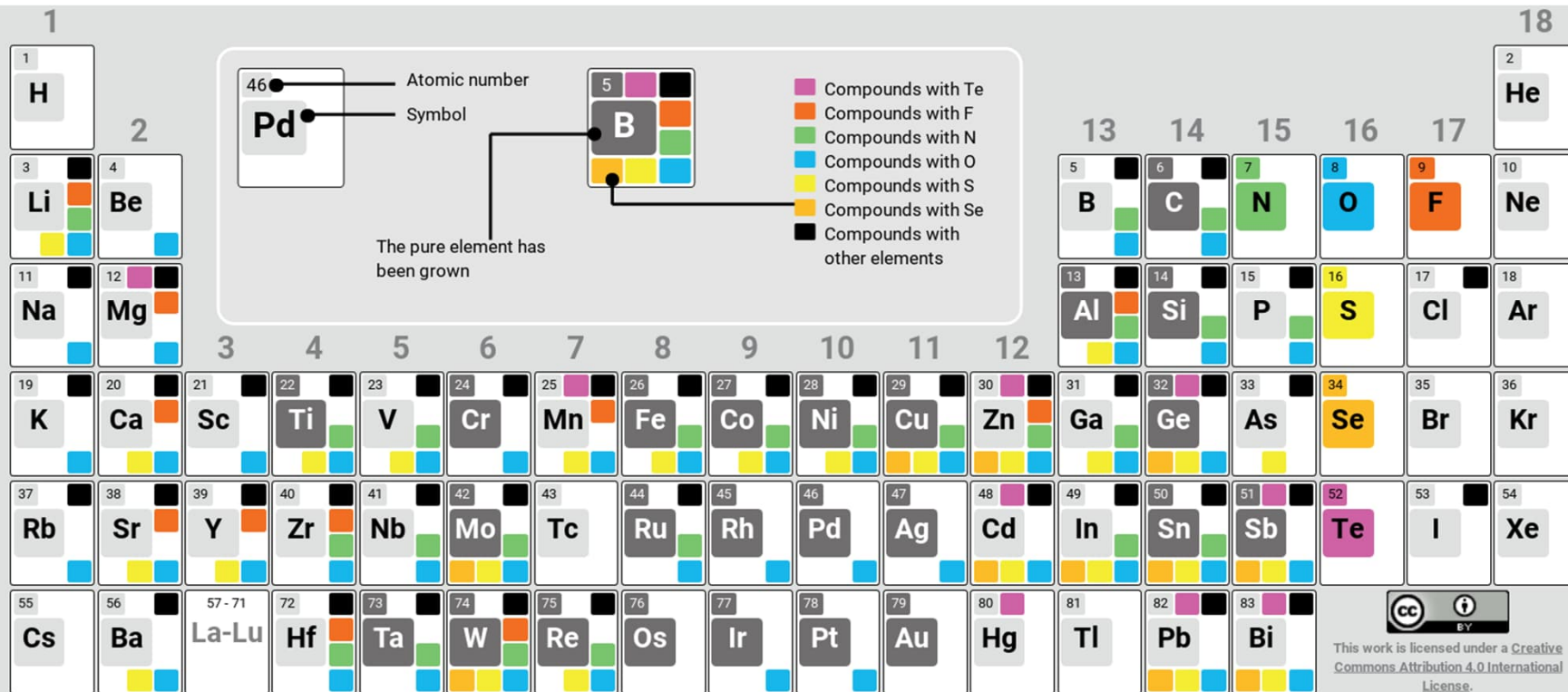


amido complexes

Common **CO-REACTANTS** (second precursor):

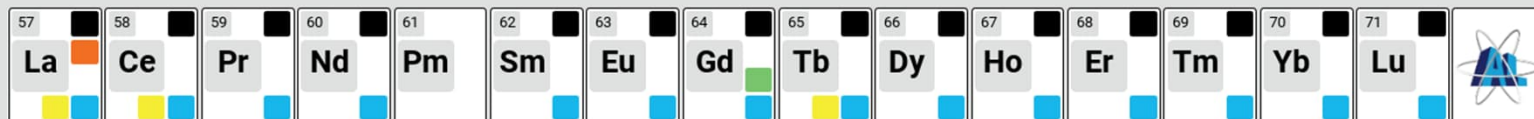
- Water  $\text{H}_2\text{O}$  (e.g. with  $\text{TiCl}_4$  or  $\text{Zn}(\text{CH}_2\text{CH}_3)_2$ ) → **Oxides**
- Ozone  $\text{O}_3$  (e.g. with metal  $\beta$ -diketonates) → **Oxides**
- Dihydrogensulfide  $\text{H}_2\text{S}$  (e.g. with  $\text{ZnCl}_2$ ) → **Sulfides**
- Ammonia  $\text{NH}_3$  → **Nitrides**

# Periodic Table of ALD Processes



This work is licensed under a Creative Commons Attribution 4.0 International License.

Lanthanoids



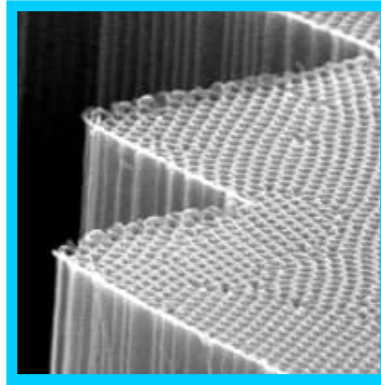
www.AtomicLimits.com - DOI: [10.6100/alddbbase](https://doi.org/10.6100/alddbbase)



# Advantages of ALD

- Relatively inexpensive method
- Excellent repeatability
- Dense and pinhole-free films
- Accurate and simple thickness control
- Large area uniformity

- Excellent conformality



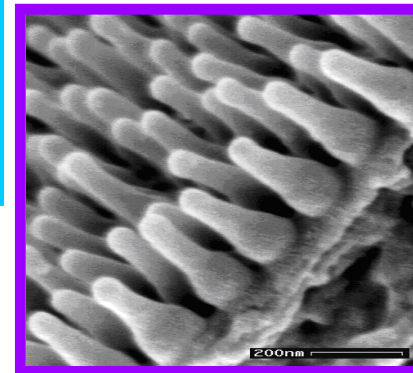
- Low deposition temperature
- Gentle deposition process

- Organic/polymer films
- Inorganic/organic hybrid materials

ELECTRONICS

NANO

BIO



NEW

**Kalevala Koru  
(Finland):**

**- traditional  
silver  
jewelry**



**Beneq (Finland):  
- Al<sub>2</sub>O<sub>3</sub> coating by ALD**

**uncoated**

**Al<sub>2</sub>O<sub>3</sub>-coated**



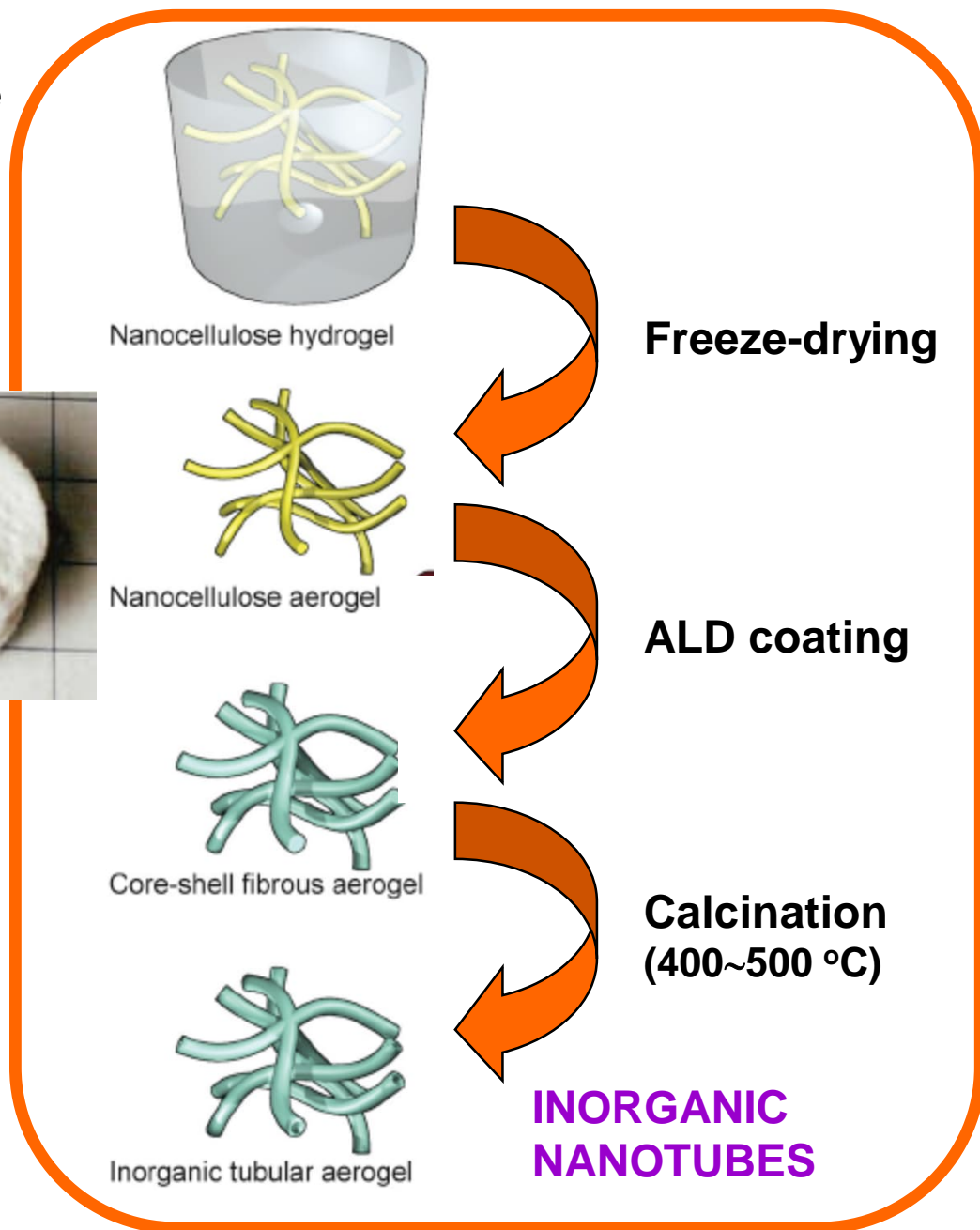
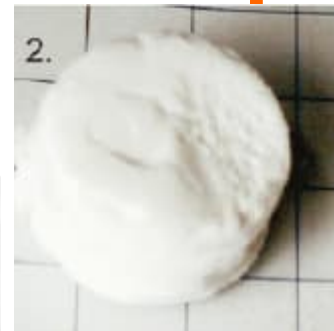
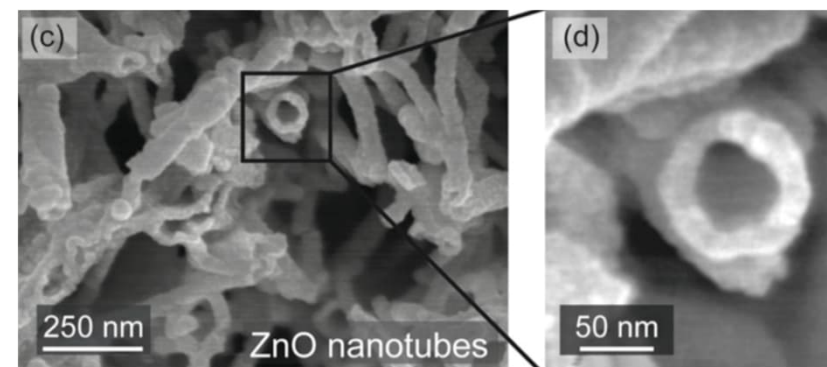
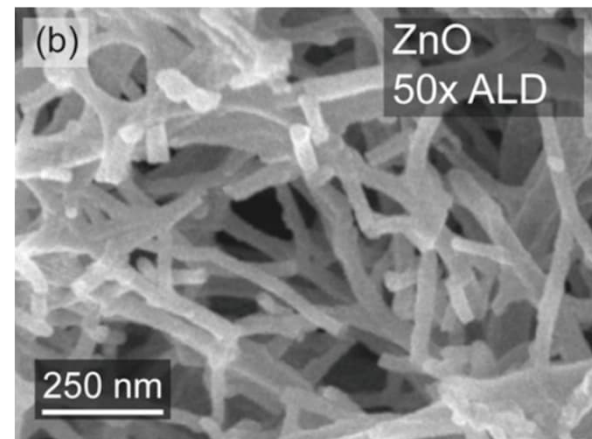
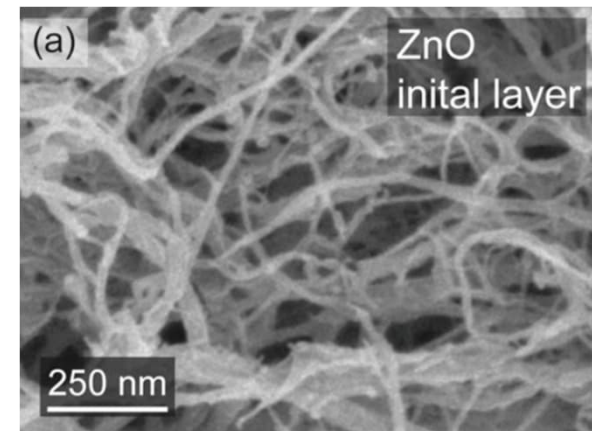
**BEFORE**

**AFTER TARNISHING TEST**

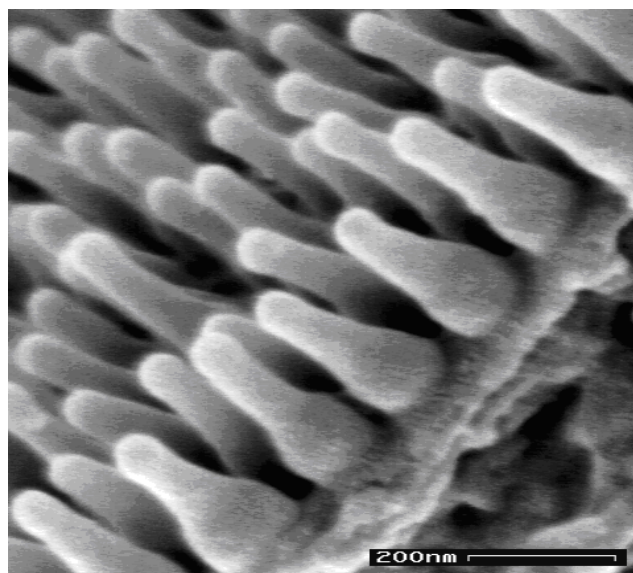
**Dense, pinhole-free  
& highly **conformal**  
ALD-Al<sub>2</sub>O<sub>3</sub>-nanocoating  
efficiently protects  
silver jewelries  
from tarnishing**

# NANOSTRUCTURING by ALD

## - nanocellulose aerogel template



J.T. Korhonen, J. Malm, M. Karppinen,  
O. Ikkala & R.H.A. Ras, *ACS Nano* 5, 1967 (2011).



## CICADA WING

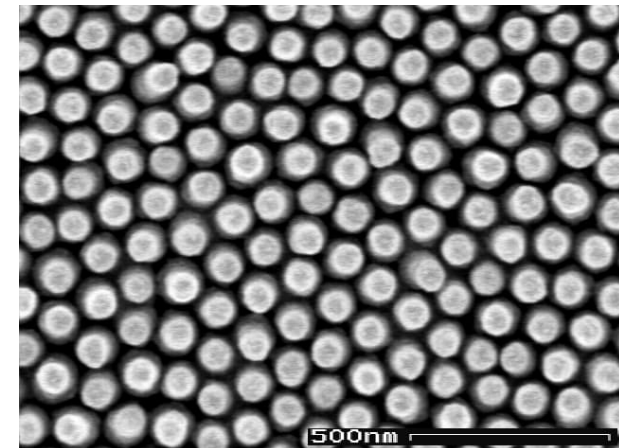
- Peculiar surface-nanostructure  
200-nm high nanopillars coated with a waxy layer
- **superhydrophobic**

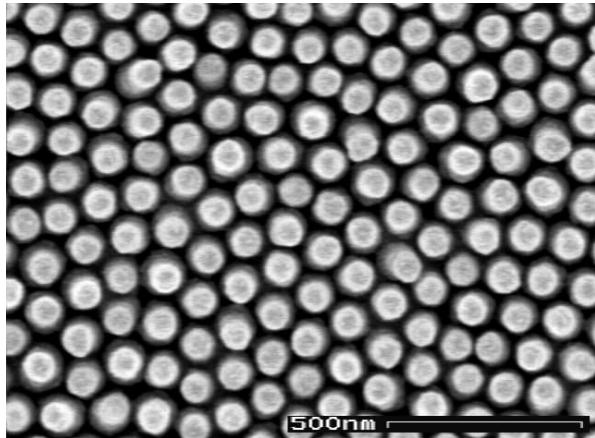
## ZnO

- **Reversible change** from hydrophobic to hydrophilic upon UV-radiation

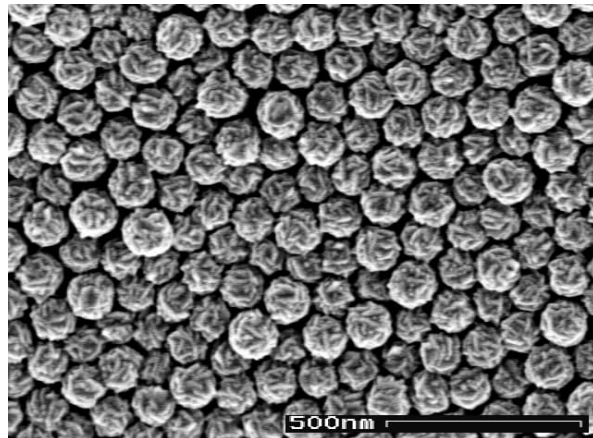
## CICADA WING + ZnO

- Conformal coating of the **wing** by a thin layer of **ZnO** (~20 nm) by means of **ALD**
- **Reversible change** from **superhydrophobic** to **superhydrophilic** upon UV-radiation

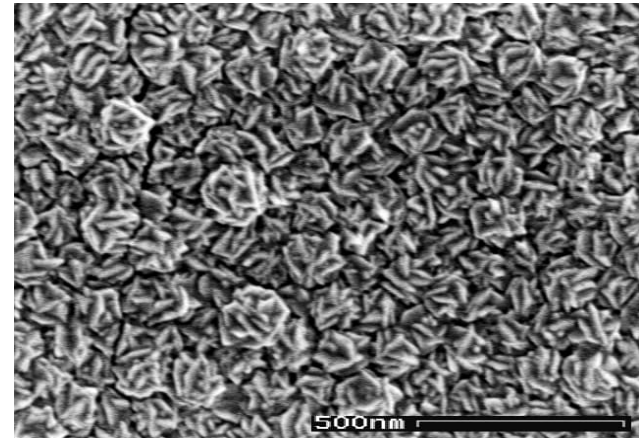




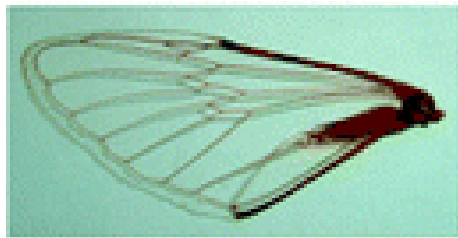
100 cycles (20 nm)



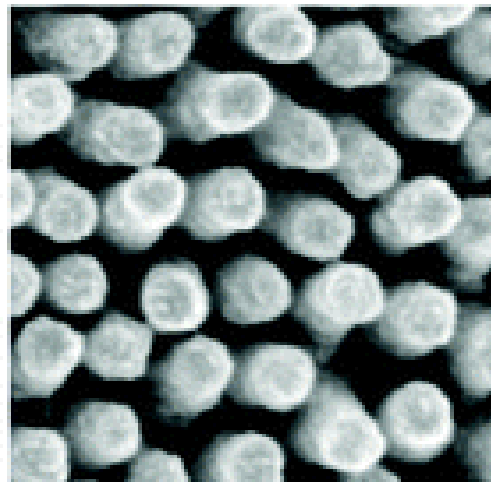
300 cycles (60 nm)



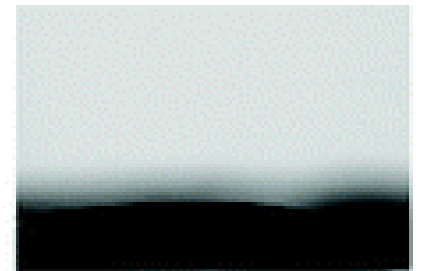
500 cycles (100 nm)



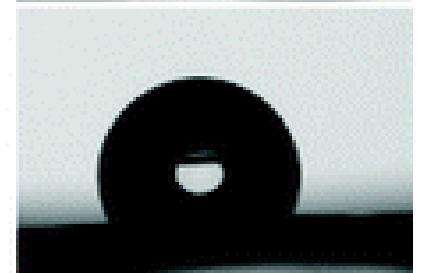
ALD  
→

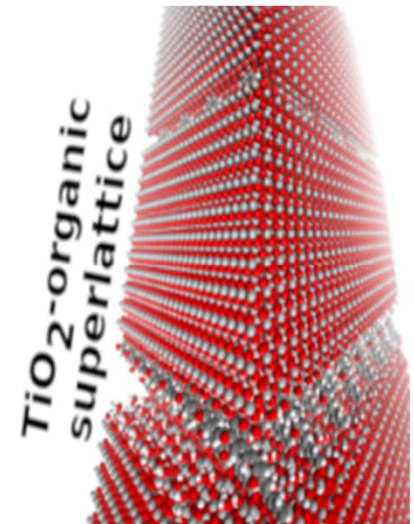
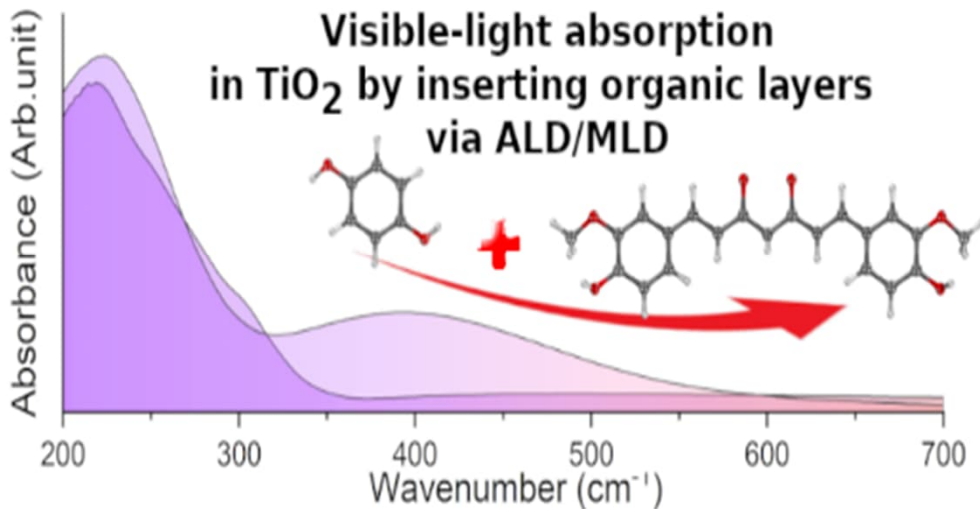
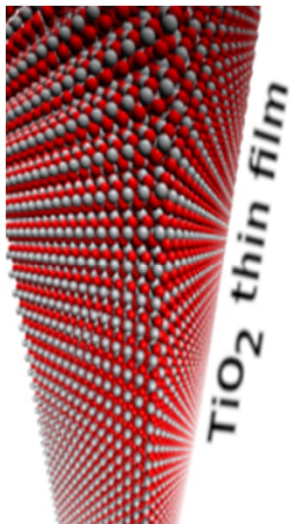
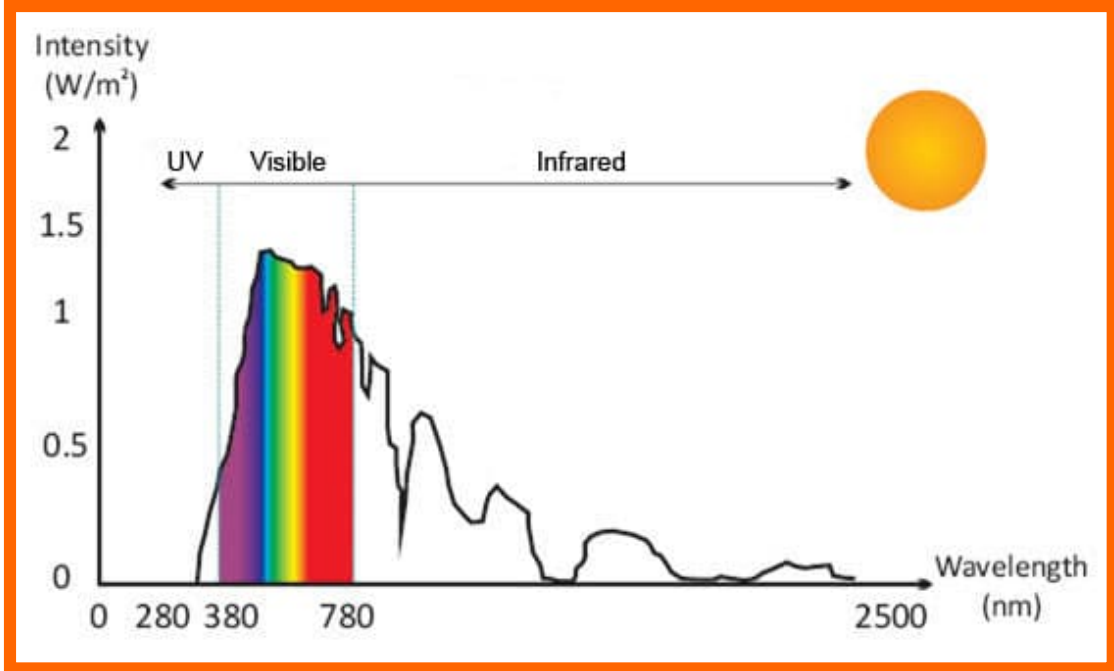


UV  
→



→  
dark





Visible-light absorbing TiO<sub>2</sub>:curcumin thin films with ALD/MLD, A. Philip, R. Ghiyasi & M. Karppinen, *ChemNanoMat* **7**, 253 (2021).